



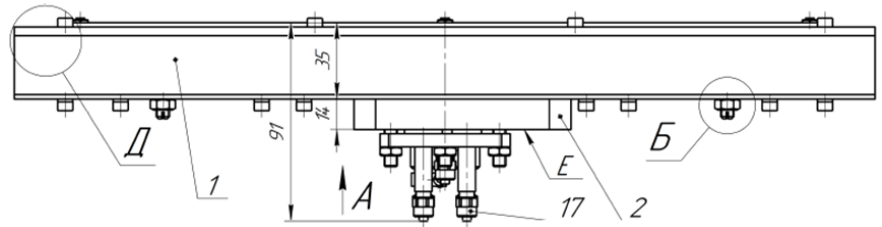
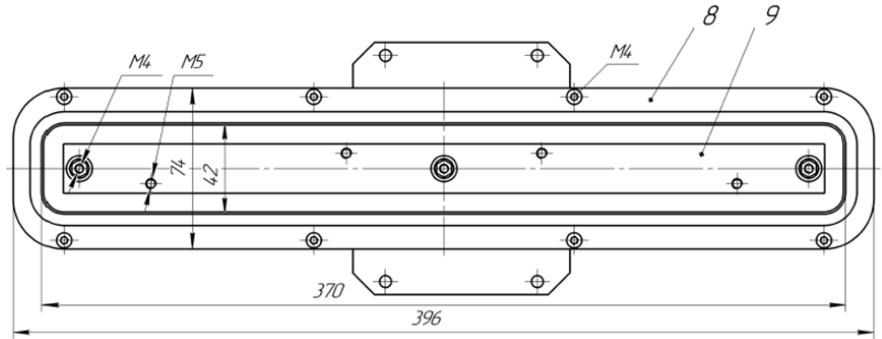
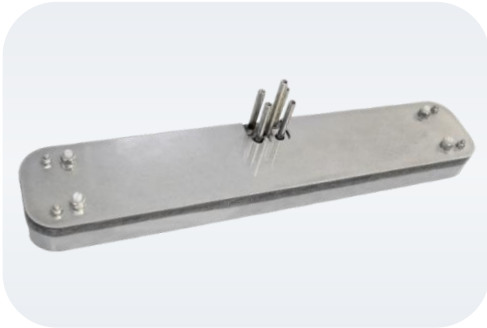
ЛЦМК.228.00.00.00

Extended ion source IBS-400 is a gas-discharge source of working gas ions with an energy of 300-2500 eV. The principle of operation is an accelerator with an anode layer (UAS).

IBS-400 is designed for a wide range of applications: ion cleaning, etching, polishing, surface modification.

Parameter	Value
Beam shape	rectangular, hollow
Beam size (L x W x T), mm <small>* (Length x Width x Thickness)</small>	370 x 42 x 5
Supply voltage, V <small>* The average ion energy of the beam is approximately equal to half the supply voltage</small>	500 – 5000
Maximum voltage, V	5500
Maximum beam current, mA <small>* For working gas - argon at a flow rate of not more than 2.0 l / h</small>	600
Maximum operating current, mA	1000
Maximum gas consumption, l / h	5,0
Maximum coolant consumption, l / min	1
Maximum working pressure in the chamber, Pa	10
Chamber working pressure range, Pa	0,001-1
Weight, kg	no more than 6

\* It is produced in several versions.



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